

# Joint SAE/JEDEC GaN and SiC Working Group

- Topics
  - Market trend of GaN and SiC devices
  - Qualification of GaN devices for Aerospace applications
  - Challenges and approach
  - Proposal/Charter
  - Gan Power device working group activities
  - Revision to MIL-PRF-19500 progress

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# Market trend of GaN devices

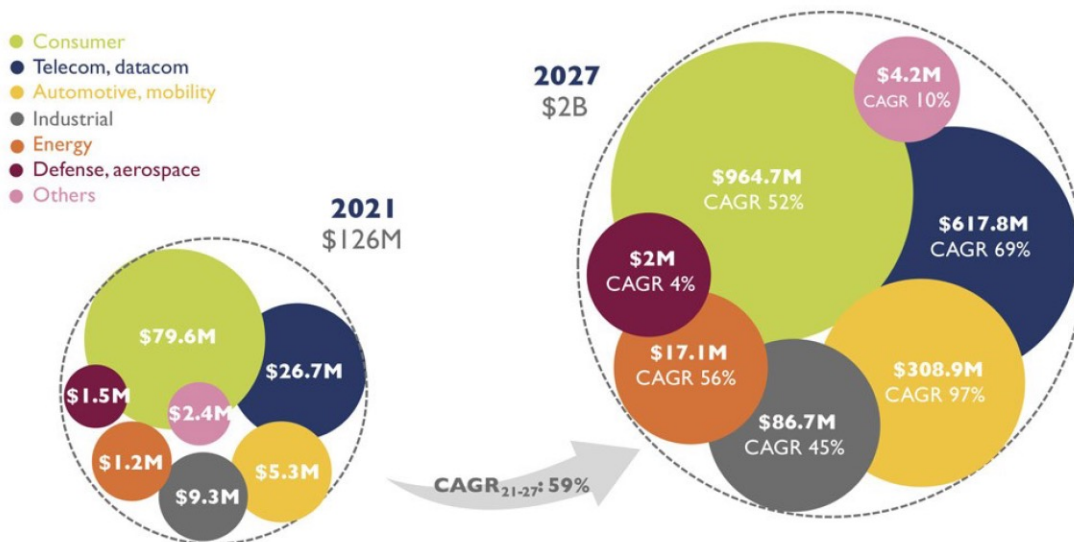
## ■ Trend

- June 2022 Semiconductor today news published the market trend for **Power Gallium Nitride (GaN)** devices.

[https://www.semiconductor-today.com/news\\_items/2022/jun/yole-130622.shtml](https://www.semiconductor-today.com/news_items/2022/jun/yole-130622.shtml)

### 2021-2027 power GaN device market revenue

(Source: Power GaN 2022 report, Yole Développement, 2022)



The power Gallium Nitride (GaN) device market is growing at a compound annual growth rate **(CAGR) of 59%** from just \$126m in 2021 to \$2bn in 2027, estimates market research and strategy consulting company Yole Développement in the latest edition of its annual report 'Power GaN 2022'.

# Market trend of SiC devices

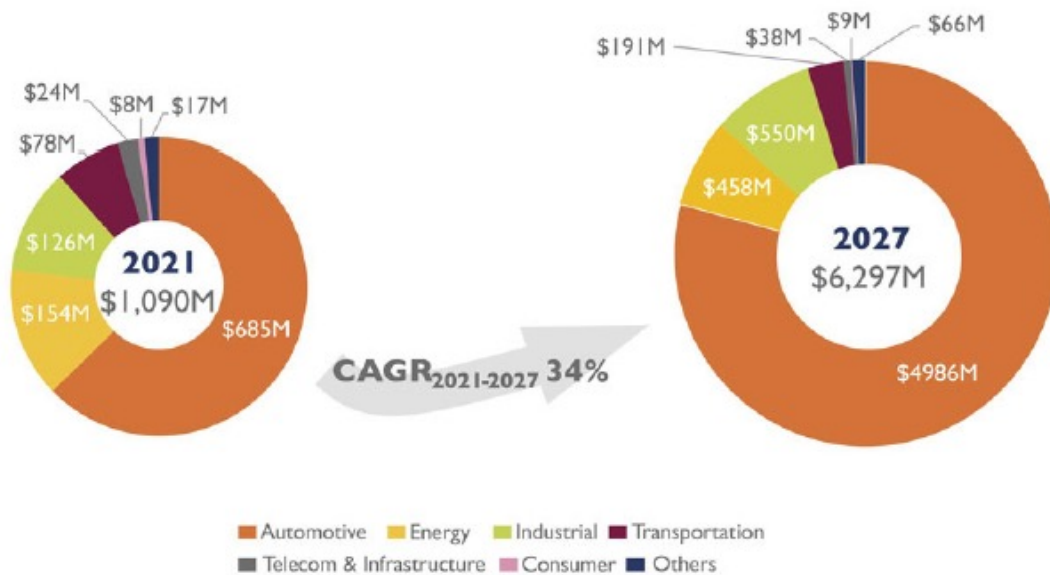
## ■ Trend

- April 2022 Semiconductor today news published the market trend for **Silicon Carbide (SiC)** devices.

[https://www.semiconductor-today.com/news\\_items/2022/apr/yole-040422.shtml](https://www.semiconductor-today.com/news_items/2022/apr/yole-040422.shtml)

### 2021-2027 power SiC market devices split by segment

(Source: Power SiC 2022 report, Yole Développement, 2022)

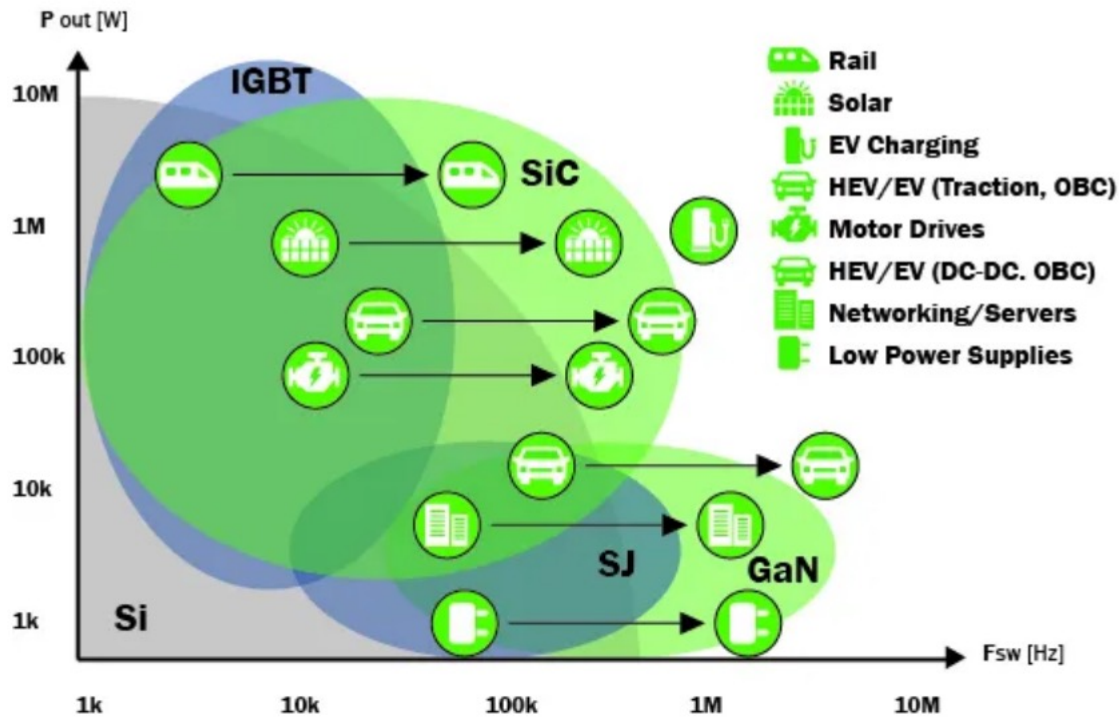


The Silicon Carbide (SiC) device market is growing at a compound annual growth rate (**CAGR**) of **34%** from just \$1.09bn in 2021 to \$6.3bn in 2027, estimates market research and strategy consulting firm Yole Development in its latest annual report 'Power SiC 2022'.

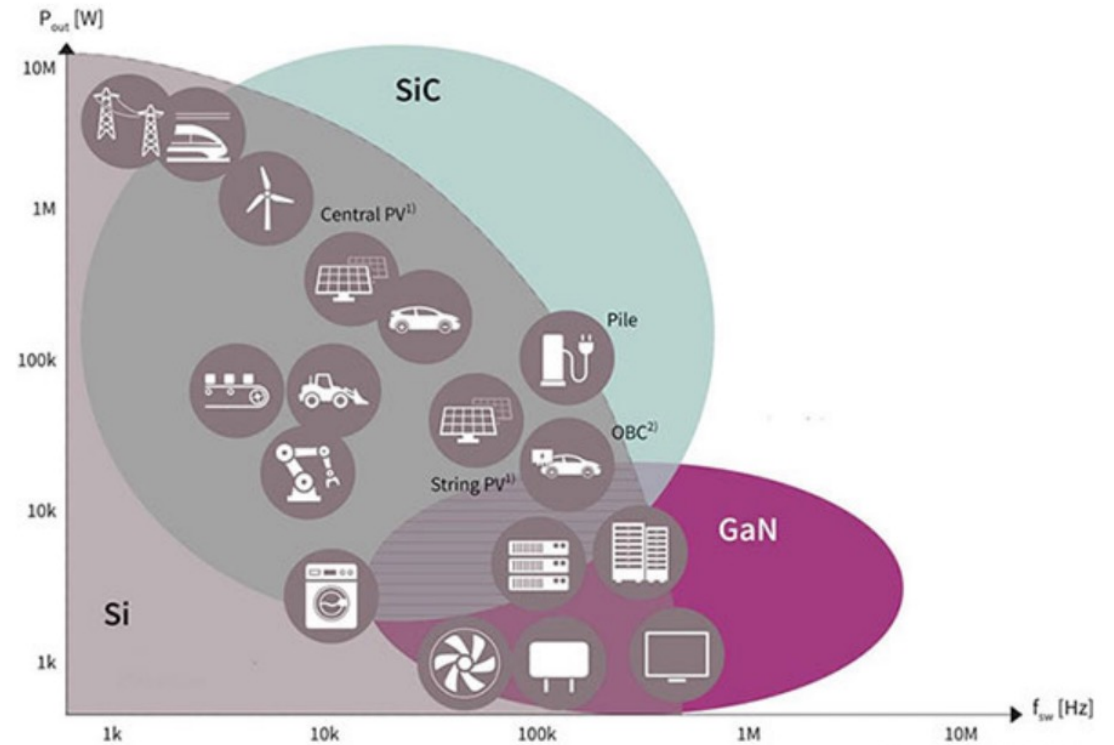
# Market trend of GaN and SiC devices

## ■ Trend

- Graphical illustration of application and advantages of GaN and SiC device technology
  - Sources from World Wide Web publications links below



<https://www.powerelectronicsnews.com/the-difference-between-gan-and-sic-transistors/>



1) PV = photovoltaic inverter

2) OBC = on-board charger

<https://nl.farnell.com/wide-bandgap-semiconductor-the-future-of-sic-and-gan-technology>

# *Qualification of GaN Power devices for Aerospace applications*

## ■ Motivation

- Extended mission life in space (could exceed 20 years)
  - Without possibility of repair or replacement specially on Satellite applications
- Harsh environment
  - Temperature, humidity, mechanical stress, radiation in space (TID, SEE, SEB) and in aircraft altitudes (Neutron, Proton)
- Safety requirements
  - Military Aircraft/Manned Spacecraft safety
- MIL-STD requirements are beyond commercial & automotive requirements
  - More stringent requirements
- Size, Weight and Power, Cost (SWaP-C)
  - Design consideration in optimizing **S**ize (smaller), **W**eight (lighter) and **P**ower (minimal lost of efficiency) which could offer lowered **C**ost in a system.

# Challenges and approach

## ■ Challenges

- Wideband Gap (WBG) devices, particularly Power GaNFETs, are relatively new, with active academia research into their reliability issues.
- Insertion of Power GaNFETs require new JEDEC standards, and new qualification procedures for use in aerospace applications.

## ■ Qualification approaches

- Most commercial manufacturers of non-hermetic or plastic packaged devices adopts the JESD94, JESD47, series of JESD22 documents, and/or customized/modified excerpts of AEC-Q100 or AEC-Q101 from Automotive industry
- While hermetic packaging for military and space application were adopting MIL-PRF-19500 or MIL-PRF-38535, with customization/modifications.

## ■ Screening approaches

- Screening is a method to remove infant mortality (marginal or weak parts) through 100% testing, seldom practiced in the commercial industry, some could be in EP product lines.

*Aerospace application currently needed significant customization to screen & qualify GaN power devices*

# The Proposal

Develop an Aerospace standard with priority on GaN power devices, which has dominant market share in the Aerospace applications.

The approach will focus on discrete GaN Power device technology using **MIL-PRF-19500** as baseline.

## Characterization and Reliability

- Failure mechanisms
- Parametric, i.e. dynamic R<sub>dson</sub>, switching
- Radiation

## Qualification

- Electrical
  - Robustness, i.e. SOA, Transient, Temperature
  - Reliability, i.e. HTRB, HTGB, HTOL, Switching-ALT
- Mechanical
  - MSL, HAST, bondpull, die shear
- Radiation
- Wafer lot acceptance

## Screening

- Burn-in (Early failures)
- Test methods

MIL-PRF-19500 – as baseline

- New technology insertion
- Gap Analysis
- Hermetic package only(?)

Applicability:

- MIL-STD-750 TM
- JC70 released Guidance doc
- Aerospace TOR
- JESD47
- JESD94

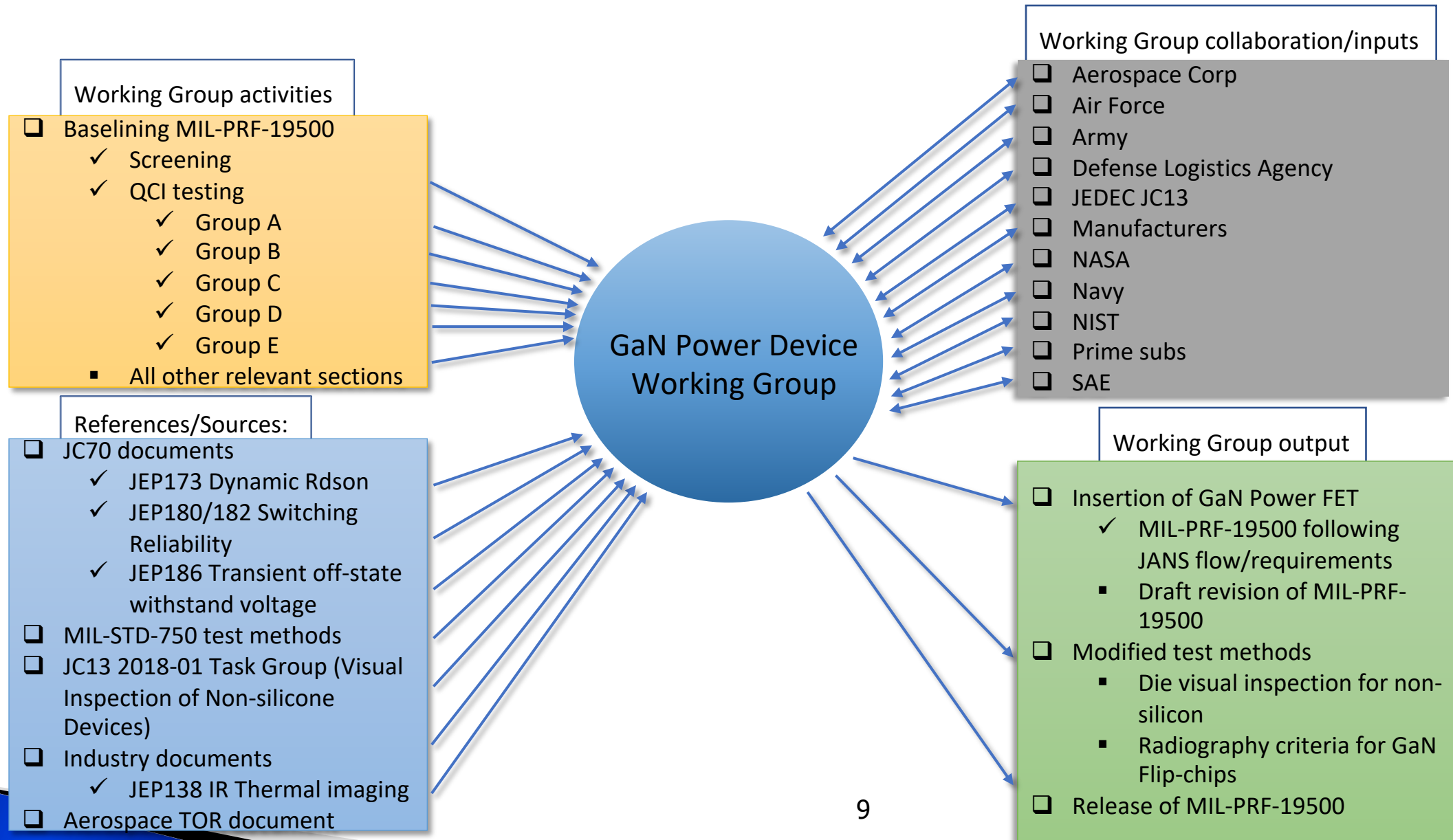
# *Joint SAE/JEDEC GaN Power device Working Group*

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- Joint SAE/JEDEC GaN Power device working group
  - CHARTER
    - The task group shall be responsible for the development and establishment of standardized screening, conformance inspection and qualification requirements of Power GaN devices (non-RF) for space application.
    - Shall utilize relevant technical information and other industry guidance or standards as appropriate.
    - Baseline the General Specification for Semiconductor devices MIL-PRF-19500 document and focus on hermetic packaged HEMT (E-Mode) discrete Power Gallium Nitride lateral technology devices only.



# Joint SAE/JEDEC GaN Power device Working Group




# MIL-PRF-19500 Screening progress update...

The documentation and process conversion measures necessary to comply with this revision shall be completed by 24 January 2022.

INCH-POUND  
MIL-PRF-19500R  
24 July 2021  
SUPERSEDING  
MIL-PRF-19500P  
W/AMENDMENT 4  
18 May 2019

**PERFORMANCE SPECIFICATION  
SEMICONDUCTOR DEVICES,  
GENERAL SPECIFICATION FOR**



MIL-PRF-19500R  
APPENDIX E  
TABLE E-IV. Screening requirements

Screen	MIL-STD-750		JANS requirements	JA req
	Method	Condition		
1a. Die visual for glass diodes	2073	Condition B, die form prior to assembly	100-percent	Not a
		100-percent	100-	
1b. Internal visual (pre-cap) inspection For diodes For power FETs For microwave transistors For transistors	2074 1/ 2069 2070 2072			
		2. High temperature life Nonoperating life (stabilization bake)	$T_{STG} \leq$ maximum rated storage temperature $t =$ as specified	Optional
3a. Temperature cycling	1051	20 cycles. No dwell time is required at +25°C. Test condition C or maximum storage temperature, whichever is less.	100-percent	100-
3b. Surge (as specified) 2/	4066	Condition A or B, as specified	100-percent	100-
3c. Thermal impedance (as specified) 2/		As specified	100-percent	100-
Diodes	3101			
Transistors, Power FETs	3161			
Bipolar	3131			
IGBT	3103			
GaAs FET	3104			

### Internal visual inspection (TM2069):

- leverage JC-13 TG 2018-02: Visual Inspection for Non-Silicon Devices
- Need updating of TM2069

### Surge current (TM4066):

- Not applicable to GaN technology
- Implement JEP186 Transient off-state withstanding voltage

### Thermal impedance (TM3161):

- Difficult to measure, require an open part to directly measure the flip-chip
- Implement instead Radiography at screening (effectiveness of bump attachment)
- Perform characterization in Group E using JEP138 IR Thermal imaging

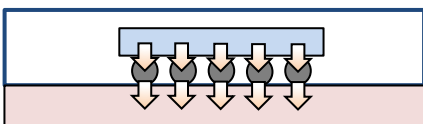
### High Temp Reverse Bias (HTRB) & High Temp Gate Bias (HTGB) TM1072:

- Implement JEP173 for Dynamic Rdson

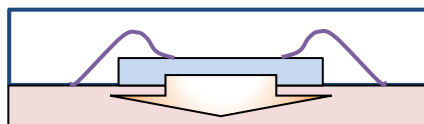
### Radiography (TM2076):

- Need updating to include flip chip mount devices, such criteria addresses this type of mounting
  - Resources: Ball Grid Array (BGA) and Land Grid Array (LGA) X-Ray criteria in MIL-STD-883, MIL-PRF-38535 & MIL-PRF-38534

Flip-chip attach



Eutectic attach



# MIL-PRF-19500 Quality Conformance Inspection progress...

## Group A

- All subgroups were deemed applicable
- Add Capacitance testing
- Switching parameter to be indirectly measured using Gate charge, Capacitance and Dynamic Rdson

## Group C

- Essential elements identified
  - Insert Die shear/Pull TM 2017 for GaN flip-chip
  - Thermal resistance to use Radiography TM2076

MIL-PRF-19500R APPENDIX E

TABLE E-V. Group A inspection – Continued.

Subgroups	MIL-STD-750, method	JANS sample plan 1/	JAN, JANTX, JANTXV sample plan 1/
Subgroup 2 DC (static) test at +25°C ±3 degrees C			
Subgroup 3 DC (static) tests at high (-0C, +10C) and low (10C) specified temperatures.			
Subgroup 4			

The documentation and process conversion measures necessary to comply with this revision shall be completed by 24 January 2022.

MIL-PRF-19500R APPENDIX E

TABLE E-VII. Group C periodic inspections (all quality levels).

Inspections	Method	Condition	Sample plan	Small lot conformance inspection
	MIL-STD-750			

MIL-PRF-19500R APPENDIX E

TABLE E-VIII. Group D inspection (RHA inspections). 1/

Subgroup	Method	Condition	Sample plan	Small lot conformance inspection
Subgroup 1 2/				

## Group D RHA

- All subgroups were deemed applicable

MIL-PRF-19500R APPENDIX E

TABLE E-IX. Group E inspections (all quality levels).

Inspections	Method	Condition	Sample plan	Small lot conformance inspection
Subgroup 1 2/				

## Group B

- Essential elements identified
  - Surge test replaced by JEP186
  - Add Dynamic Rdson (JEP173) measurement post Accelerated steady-state operational life test
  - Thermal resistance to use Radiography TM2076

## Group E

- Essential elements identified
  - Life test TM 1042 both HTRB & HTGB extend durations to 2,000 hrs @ 80% bias
  - Add Dynamic Rdson (JEP173) measurement post Life test
  - Thermal impedance characterization to use JEP138 IR Thermal imaging
  - Add subgroup 10 for Switching reliability iaw JEP180/182
  - Add subgroup 11 for Single-Event Effect (SEE) TM1080
  - Add subgroup 12 for JEP186 Transient off-state withstanding voltage test

PERFORMANCE SPECIFICATION SEMICONDUCTOR DEVICES, GENERAL SPECIFICATION FOR



QCI testing is a validation of a specific production lot to be used for flight meets the requirements



# Joint SAE/JEDEC GaN and SiC Working Group

- Task group information:
  - Joint SAE/JEDEC GaN and SiC Working group is leading this task activity, chaired by Rod de Leon/Boeing
  - Kick-off meeting started Feb 15<sup>th</sup> 2023 with bi-monthly meeting that officially started last March 2<sup>nd</sup>, 2023.
  - Members to date includes the following Organization:
    - Aerospace Corp, Airbus, BAE, Ball Aerospace, Boeing, DLA, DLR(Tesat), EPC Space, ESA, Golden Altos, Infineon, Integra, LMCO, Maxar, Microchip, NASA (MSFC/GSFC/JPL), Navy-CRANE, NIST, Renesas, SAE, Texas Inst, Teledyne, US-Air Force, US-Army